MPI TS2500-SE | 200 mm Fully Automated Probe System with ShielDEnvironment™

For Accurate and Reliable 24/7 Production Tests at a Wide Temperature

Software Suite SENTIO®

- Revolutionary multi-touch, single window GUI for easy and intuitive system operation
- Scroll, zoom, move commands mimic modern smart mobile devices making everyone the operation expert just in minutes
- Switching between applications is just a matter of a finger swipe
- Integrated workflow with MPI RF calibration software QAlibria® provides unparalleled user experience
- GPIB, TCP/IP interface for remote control

Thermal Control

- Thermal chuck can be operated by using the fully integrated touch-screen display
- Placed at convenient location in front of the operator for fast operation and immediate feedback

Microscope and Optics Options

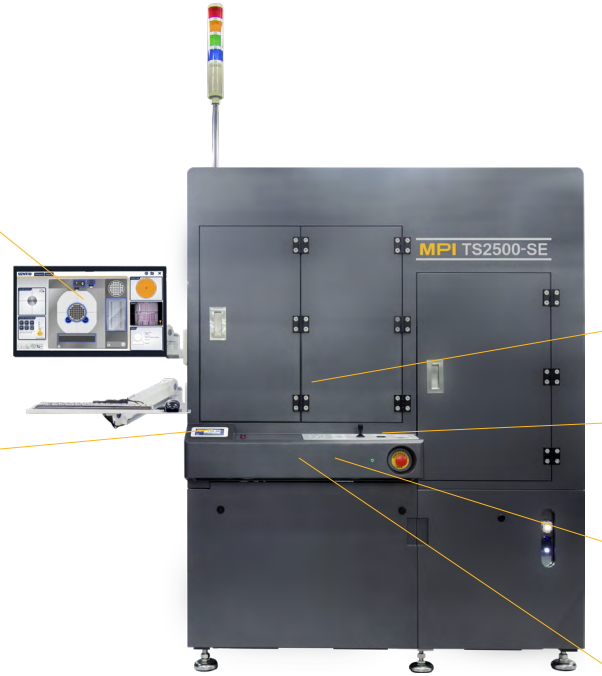
- Stable microscope bridge mount with 50 x 50 x 140 mm programmable movement
- Various optics options available such as MPI AMZ12 with up to 12x optical zoom or MPI iMAG® - the digital microscope

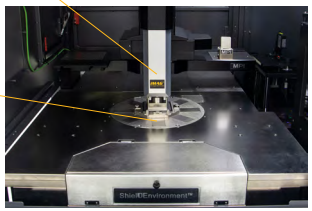
ShielDCap™

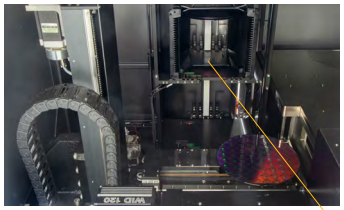
- Consequent shielding and easy re-configuration
- Allows up to 4-port RF or up to 8-ports DC/Kelvin or a combination of those configurations
- Probe card version available

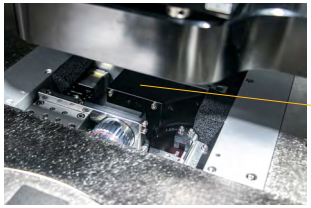
MicroPositioners

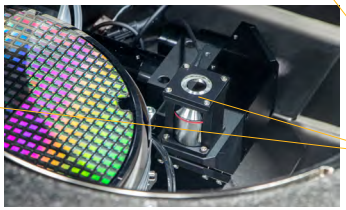
- Supports up to 8 DC or 4 RF and 4 DC MicroPositioners
- Wide range of MicroPositioners available, including programmable and large area for mmW applications
- Dedicated Coax, Triax and Kelvin probe arms
- 4.5” / 6.5” probe card holder: standard or dedicated for long term measurements











RF Calibration

- Integrated two auxiliary chucks for RF calibration substrates
- Built-in ceramic for accurate calibration up to THz frequencies
- 1 µm flatness for consistent contact across the wafer

Production Reliability

- Designed for 24/7 production reliability
- Safety cover with interlocks providing a closed environment

Integrated Hardware Control Panel

- Faster, safer and more convenient system operation and control
- Keyboard and the mouse are at the system control panel for a single-point operation with the system and controlling test instrumentation

ShielDEnvironment™

- Advanced EMI / RFI / Light-tight shielding for the best in class 1/f noise test results
- fA low-leakage capabilities

AirCool® PRIME Thermal Chuck

- Designed by MPI and ERS for faster transitions and reduced soaking time
- Wide temperature range -60 °C to 300 °C with unique configuration capabilities
- Convenient location of the control panel for fast and easy interaction with the system
- Reduced footprint by smart integration of the chiller space
- Significant savings via recycling of chuck air for purge application

Wafer Loading

- Standard two cassettes for 100, or 150 or 200 mm wafers

Available Options

- Standard off-axis wafer alignment camera
- Optional upward looking chuck camera for probe-to-pad alignment